

**Increasing Stability of Meso/Micro Milling Cutting** by means of Ultrasonic Vibration Assisted Machining

Paolo Parenti\*, Chaneel I. Park\*\*, Simon S. Park\*\*, Massimiliano Annoni\*

\*Dept. of Mechanical Engineering, Politecnico di Milano \*\*Dept. of Mechanical and Manufacturing Engineering, University of Calgary



# **Ultrasonic Vibration Assisted Machining**

- **Chip Removal** (cutting kinematics and cutting action)
- Cutting force reduction (friction) •
- Machinable Materials (hard/brittle)
- **Burr formation**

# Milling Process instability (Regenerative Chatter)

- Poor Surface finish
- **Reduced Productivity**
- **Excessive Tool Wear**
- **Tool Breakage**



• **Toll Wear** (including thermal and chemical)

## **Process Improvement**

### **GOALS**:

- To verify experimentally the force reduction by applying **UVAM** in different directions with very high vibration frequency
- To investigate the increased cutting stability with respect to the regenerative chatter phenomenon

# **Experimental Setup**

Kern CNC machining center Spindle: 60000 / 150,000 rpm Resolution 0.1 µm Positioning tolerance ±1.0 µm Controller Heidenhain



## to avoid

# Effects on Cutting Stability

- **Cutting Coefficients reduction (rake angle)**
- **Tool dynamic modification (clamping)**
- **Increased Process damping**





# **Dynamic Charachterization**



	0.30	!	!	!
	0.25	 · · ·		
obes Diagram	0.20	 · · · · ·		
Calculation	۳ ۳ ۵.15	 		/ i

End mill 2 Flutes Diameter=500µm Edge radius≈2µm Helix=30° / Clearance=10° Young's Module≈690Gpa

## **Piezo-Electric Actuators**

**3-Axial Vibration at 20KHz** #2 **L**# Workpiece etup Aluminum Q tu Ð S S





 Reduction of cutting forces are measured through dynamometer during stable cutting



- Chatter detection is based on AE sensor/ Accelerometer
- Stability Lobes diagram is verified with and without application of UVAM technique

 Effects of high assisting frequency (>100KHz) are investigated and compared with lower frequency (20KHz) Process cutting modelling through Mechanistic and FEM approach are foreseen

Coupling (RC)

Receptance

Industrial exploitability of the solution is also addressed



**RF** Amplifier

Micro Engineering **Dynamics** Automation Lab (MEDAL)

#### **Corresponding Authors:**

Prof. Simon Park simon.park@ucalgary.ca http://www.ucalgary.ca/medal/ Tel: 403 220 6959

Prof. Massimiliano Annoni massimiliano.annoni@polimi.it http://www.mecc.polimi.it/ Tel: (+39) 02 2399 8536

